

**Agenda**

Wednesday, May 19, 2021 from 3:00 p.m. (ET)

- I. Welcome and Roll Call
- II. Announcements and Updates
- III. Approval of Minutes
- IV. Final Review and Vote on the Committee's Draft Report
- V. Public Comment
- VI. Next Steps
- VII. Adjournment

Dated: April 22, 2021.

**David Mussatt,**

*Supervisory Chief, Regional Programs Unit.*

[FR Doc. 2021-08788 Filed 4-27-21; 8:45 am]

**BILLING CODE P**

**DEPARTMENT OF COMMERCE****Bureau of the Census****Census Scientific Advisory Committee**

**AGENCY:** Bureau of the Census, Department of Commerce.

**ACTION:** Notice of public virtual meeting.

**SUMMARY:** The Bureau of the Census (Census Bureau) is giving notice of a virtual meeting of the Census Scientific Advisory Committee (CSAC). The Committee will address ongoing outreach efforts needed to assist with the designing of a differential privacy suite for the 2020 Census data products that will meet programmatic, legal, and statistical requirements, including work on both the primary and secondary disclosure avoidance systems. Last-minute changes to the schedule are possible, which could prevent giving advance public notice of schedule adjustments. Please visit the Census Advisory Committees website at <http://www.census.gov/cac> for the CSAC meeting information, including the agenda, and how to join the meeting.

**DATES:** The virtual meeting will be held on:

- Tuesday, May 25, 2021, from 11:00 a.m. to 2:30 p.m. EDT

**ADDRESSES:** The meeting will be held via the WebEx platform at the following presentation link: <https://uscensus.webex.com/uscensus/onstage/g.php?MTID=e351f8ffcb2e21b2437a649a206a6d8d3>.

For audio, please call the following number: 1-888-469-2085. When prompted, please use the following Password: #Censusdata1 and Passcode: 2886934.

**FOR FURTHER INFORMATION CONTACT:** Shana Banks, Advisory Committee Branch Chief, Office of Program, Performance and Stakeholder

Integration (PPSI), [shana.j.banks@census.gov](mailto:shana.j.banks@census.gov), Department of Commerce, U.S. Census Bureau, telephone 301-763-3815. For TTY callers, please use the Federal Relay Service at 1-800-877-8339.

**SUPPLEMENTARY INFORMATION:** The Committee provides scientific and technical expertise to address Census Bureau program needs and objectives. The members of the CSAC are appointed by the Director of the Census Bureau. The Committee has been established in accordance with the Federal Advisory Committee Act (Title 5, United States Code, Appendix 2, Section 10).

All meetings are open to the public. A brief period will be set aside during the virtual meeting for public comments on May 25, 2021. However, individuals with extensive questions or statements must submit them in writing to [shana.j.banks@census.gov](mailto:shana.j.banks@census.gov), (subject line "CSAC Differential Privacy Virtual Meeting Public Comment").

Ron S. Jarmin, Acting Director, Bureau of the Census, approved the publication of this Notice in the **Federal Register**.

Dated: April 23, 2021.

**Sheleen Dumas,**

*Department PRA Clearance Officer, Office of the Chief Information Officer, Commerce Department.*

[FR Doc. 2021-08841 Filed 4-27-21; 8:45 am]

**BILLING CODE 3510-07-P**

**DEPARTMENT OF COMMERCE****Foreign-Trade Zones Board**

[B-31-2021]

**Foreign-Trade Zone (FTZ) 45—Portland, Oregon; Notification of Proposed Production Activity; Lam Research Corporation (Semiconductor Production Equipment, Subassemblies and Related Parts), Tualatin and Sherwood, Oregon**

The Port of Portland, grantee of FTZ 45, submitted a notification of proposed production activity to the FTZ Board on behalf of Lam Research Corporation (Lam), located in Tualatin and Sherwood, Oregon. The notification conforming to the requirements of the regulations of the FTZ Board (15 CFR 400.22) was received on April 14, 2021.

Lam already has authority to produce semiconductor production equipment, subassemblies and related parts within Subzone 45H. The current request would add finished products and foreign status materials/components to the scope of authority. Pursuant to 15

CFR 400.14(b), additional FTZ authority would be limited to the specific foreign-status materials/components and specific finished products described in the submitted notification (as described below) and subsequently authorized by the FTZ Board.

Production under FTZ procedures could exempt Lam from customs duty payments on the foreign-status materials/components used in export production. On its domestic sales, for the foreign-status materials/components noted below and in the existing scope of authority, Lam would be able to choose the duty rates during customs entry procedures that apply to the finished products in its existing scope of authority and to the finished products listed below (duty free).

Lam's proposed finished products include tools and process modules for—and installation, maintenance, repair, retrofit, and upgrade kits for tools and process modules for—the following: Chemical vapor deposition, physical vapor deposition, and plasma dry etch of materials on a wafer for semi-conductor production; plasma etch of the bevel edge of a wafer to remove yield-limiting residues and defects of a wafer surface for semi-conductor production; stripping of photoresist material on a wafer for semi-conductor production; ultraviolet thermal processing of a wafer surface for semi-conductor production; and, wafer cleaning between chip-processing steps to remove yield-limiting residues and defects of a wafer surface for semi-conductor production.

Lam's proposed finished products also include installation, maintenance, repair, retrofit, and upgrade kits for the following: Machines for the production of semiconductors, namely etch systems; machines for manufacturing masks and assembling electronic circuits; semiconductor equipment and parts and assemblies; chemical/mechanical planarization and other wafer surface modification equipment; conductor material deposition process modules and machines for wafer packaging; transport modules; and, wafer transport robots.

Finally, Lam's proposed finished products include: Chemical/mechanical planarization and other wafer surface modification equipment; conductor material deposition process modules and machines for wafer packaging; transport modules; and, wafer transport robots. Lam would be able to avoid duty on foreign-status components which become scrap/waste. Customs duties also could possibly be deferred or reduced on foreign-status production equipment.